O I P Form PTO-1449 ATTORNEY DOCKET NO. SERIAL NO. 10030753 APPLICANT 10/765647 LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE Laura Wills Mirkarimi STATEMENT FILING DATE GROUP (Use several sheets if necessary) January 26, 2004 1765

## **REFERENCE DESIGNATION**

## **U.S. PATENT DOCUMENTS**

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## **FOREIGN PATENT DOCUMENT**

	DOCUMENT NUMBER	DATE	NAME	TRANSLATI YES NO
/DD/	1 528 592 A2	05/04/2005	EP	

/DD/	OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)  Flanders, D. C. et al.; "Reactive Ion Etching of Indium Compounds using Iodine Containing Plasmas"  J. Vac. Sci. Technology, B8 (6) Nov/Dec 1990, pp. 1990-1993.				
/DD/	Liu, J. Q. et al., "Dry Etching Process in InP Gunn Device Technology Utilizing Inductively Coupled Plasma (ICP) System", 10th Intern. Conf. on Indium Phosphide and Related Materials, May 11-15, 1998, Tsukuba Japan, pp. 187-190.				
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<sup>\*</sup> Copies of these references are not enclosed Pursuant to 37 CFR 1.98(d). (See accompanying IDS)

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